MAR 2 4 2004 %

4.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Application of:

Yu-Chih Lai

Group Art Unit: 1763

Serial No.:

10/092,977

Examiner: Hassanzadeh, Parviz

Filed:

Mar. 7, 2002

In Response to Office Action

Dated: Mar. 9, 2004

For:

In-Situ Measurement of Wafer Position on Lower Electrode

Attorney Docket No.: 67,200-708

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandría, VA 22313-1450.

Date: 12 2004

RESPONSE TO OFFICE ACTION

Commissioner for Patents Alexandria, VA 22313-1450

Dear Sir:

In response to an Office Action mailed March 9, 2004 of a restriction requirement imposed by the Examiner, the Applicants hereby elect with traverse the prosecution of Group I, method claims 1-10.